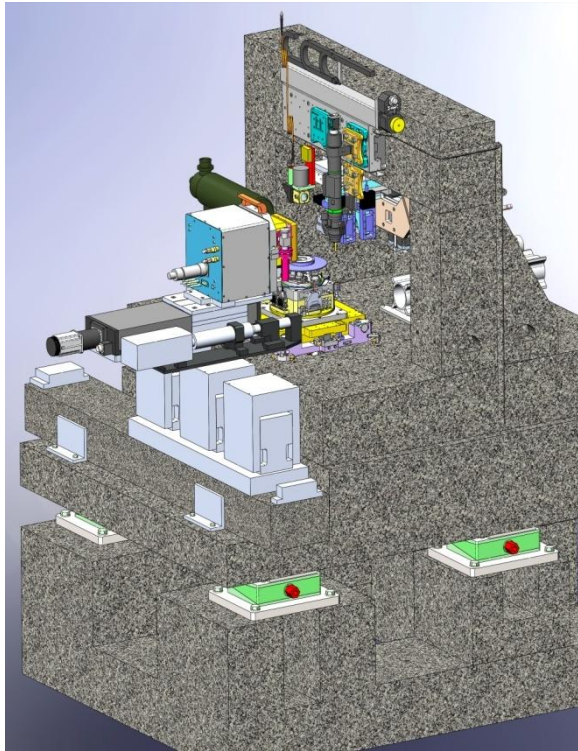




| The European Synchrotron

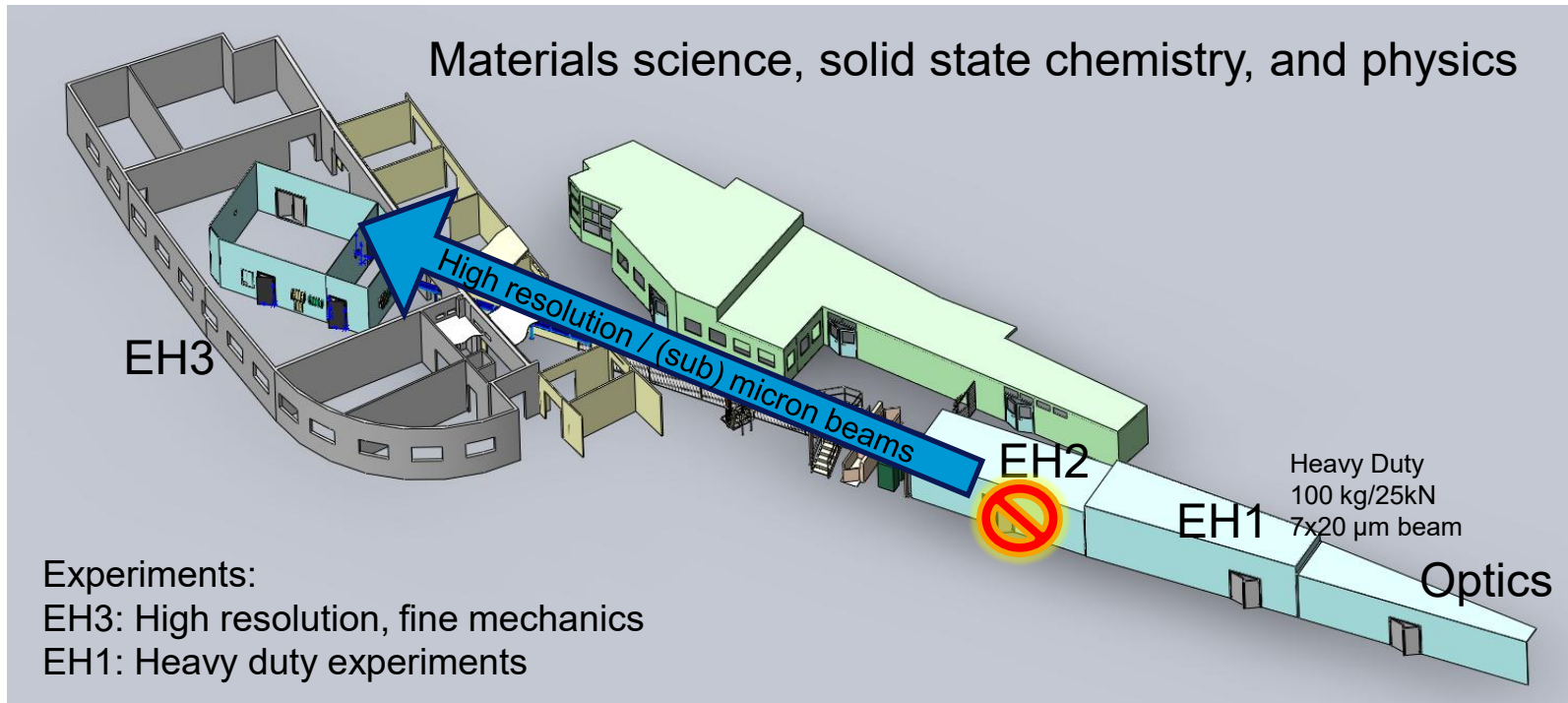


The New ID11 Nanoscope end-station A Nano-Tomography Scanner

A focus on the sample positioning stages

- I. ID11 Beamline
- II. Design architecture
- III. A rotation stage with nanometer-level performance together with an electrical slip-ring
- IV. A specific high precision linear stage
- V. Conclusion and perspectives

I. ID11 OVERVIEW

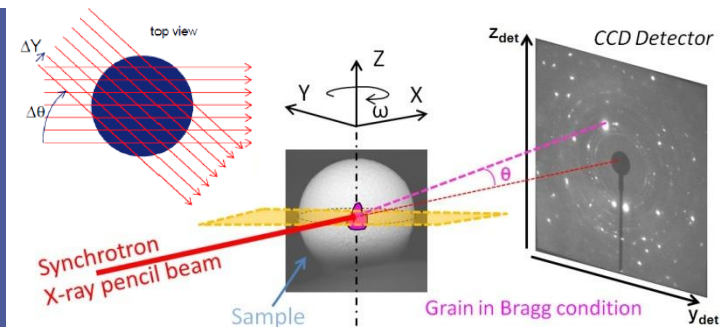


Imaging techniques on the Nanoscope :

Nano X-Ray Diffraction Computed Tomography (XRD-CT)
 Diffraction Contrast Tomography (rotation of a 3D sample)
 Fluo tomography (combination of scan and rotation)

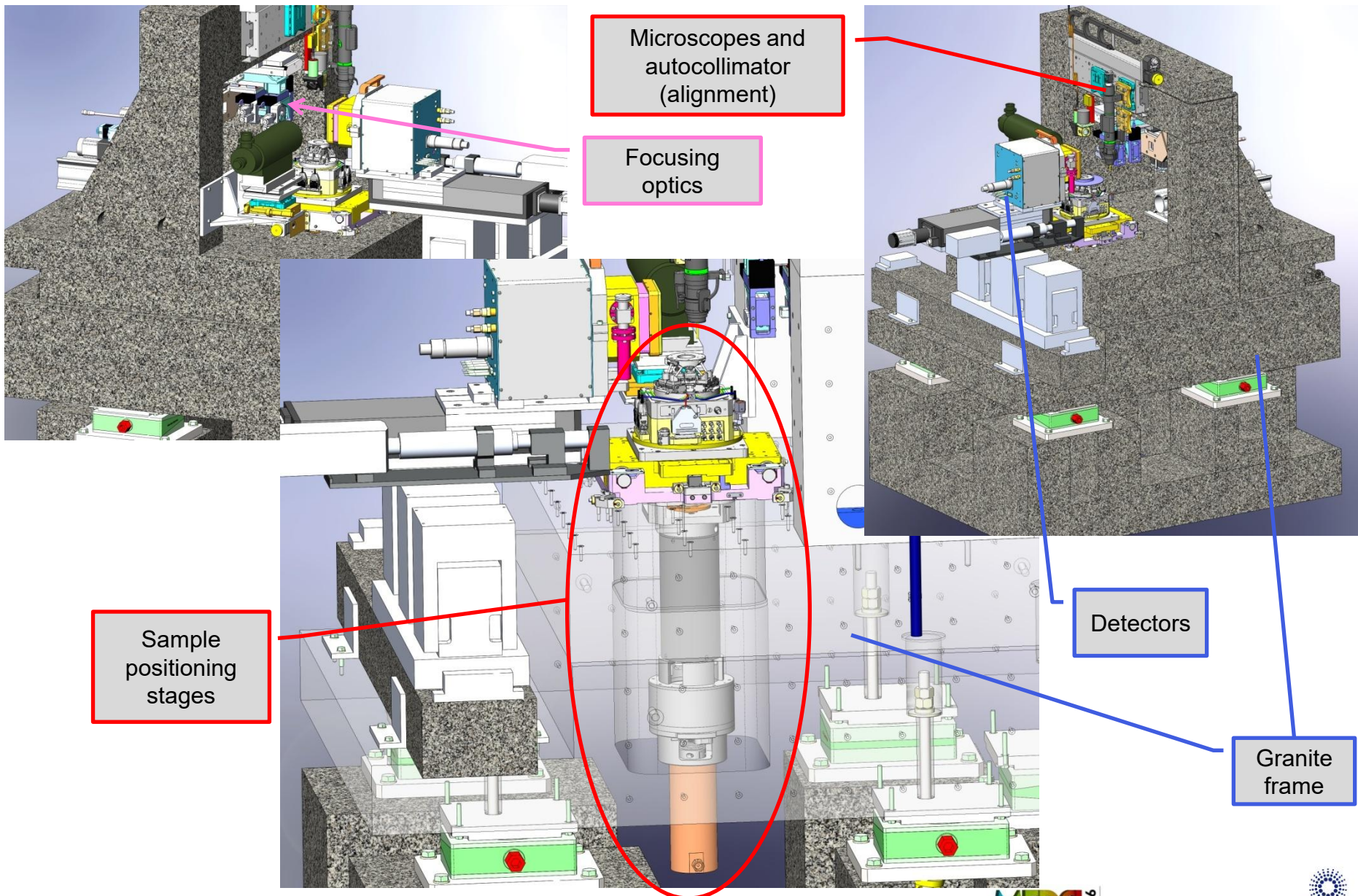
X rays

Energy from 18 to 65 keV
 Final focalisation by a set of Nano Focusing Lenses
 Typical focal spot size $\sim 100\text{nm}$

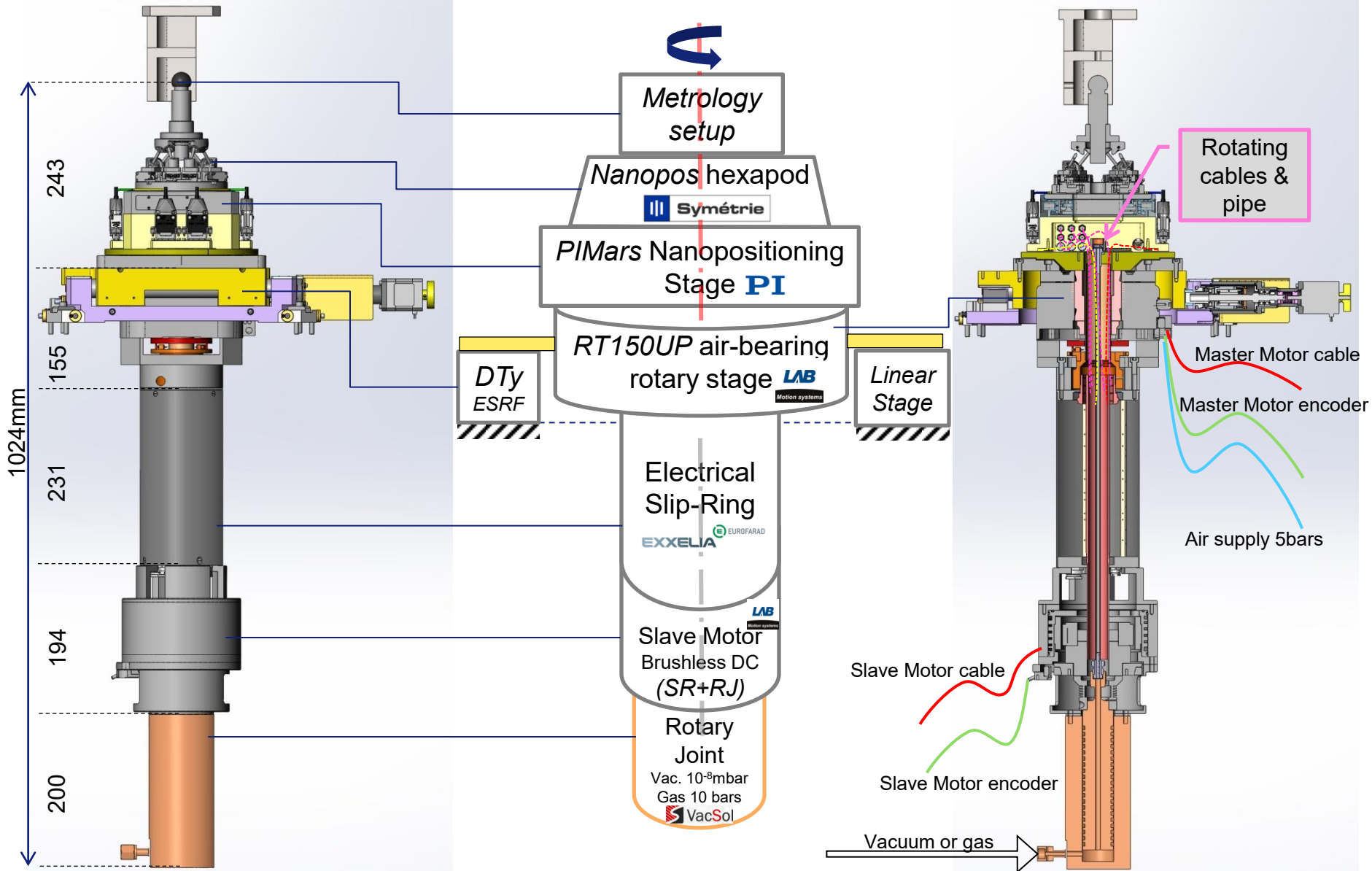


XRD-CT technique – Continuous scan in ω and incremental positions of the Y-axis

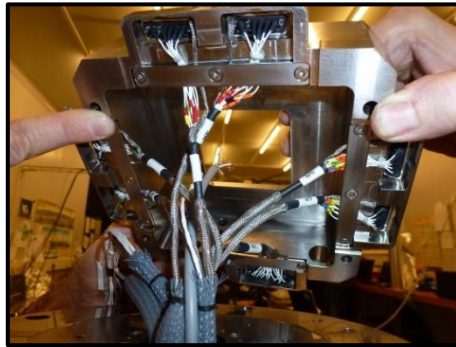
II. Design architecture - Nanoscope end-station



II. Design architecture - Nanoscope – sample positioning stages



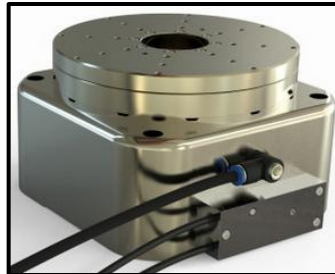
III. Design architecture - Rotation stage and slip ring



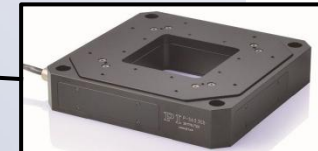
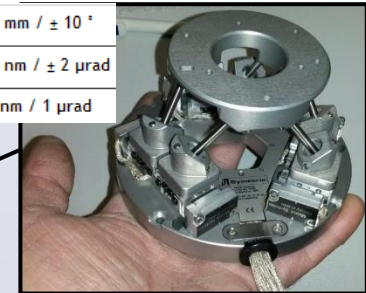
Cable box

Air bearing

Max. axial load	726	N
Max. radial load	264	N
Axial stiffness	242	N/μm*
Radial stiffness	88	N/μm*
Tilt stiffness	204 Nm/mrad	
Radial error motion	<20	nm LSC**
Axial error motion	<20	nm LSC**
Air consumption	<20	Nl/min
Total mass	15.2	kg
Material	Stainless steel	



Travel range	± 5 mm / ± 10 °
Repeatability	± 100 nm / ± 2 μrad
Resolution	10 nm / 1 μrad

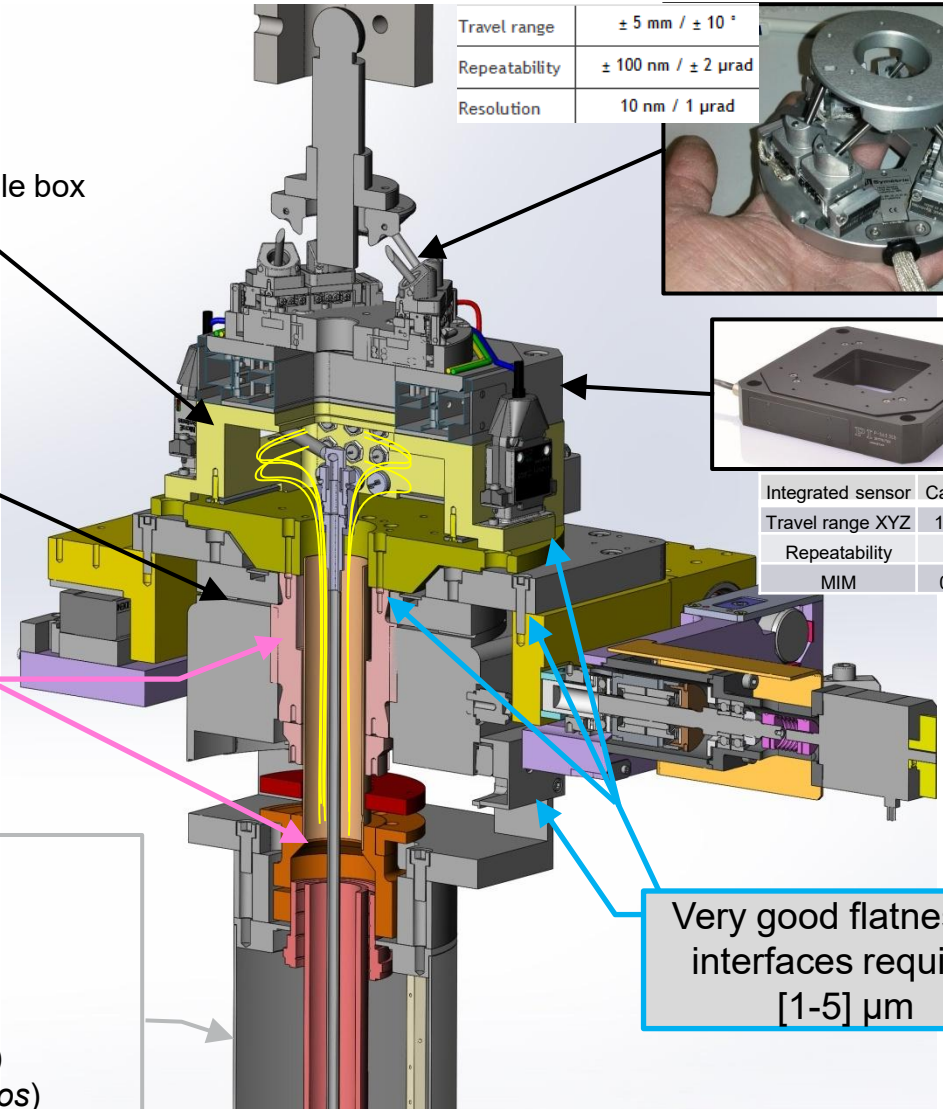


Integrated sensor	Capacitive
Travel range XYZ	150mm ³
Repeatability	2nm ³
MIM	0.8nm ³

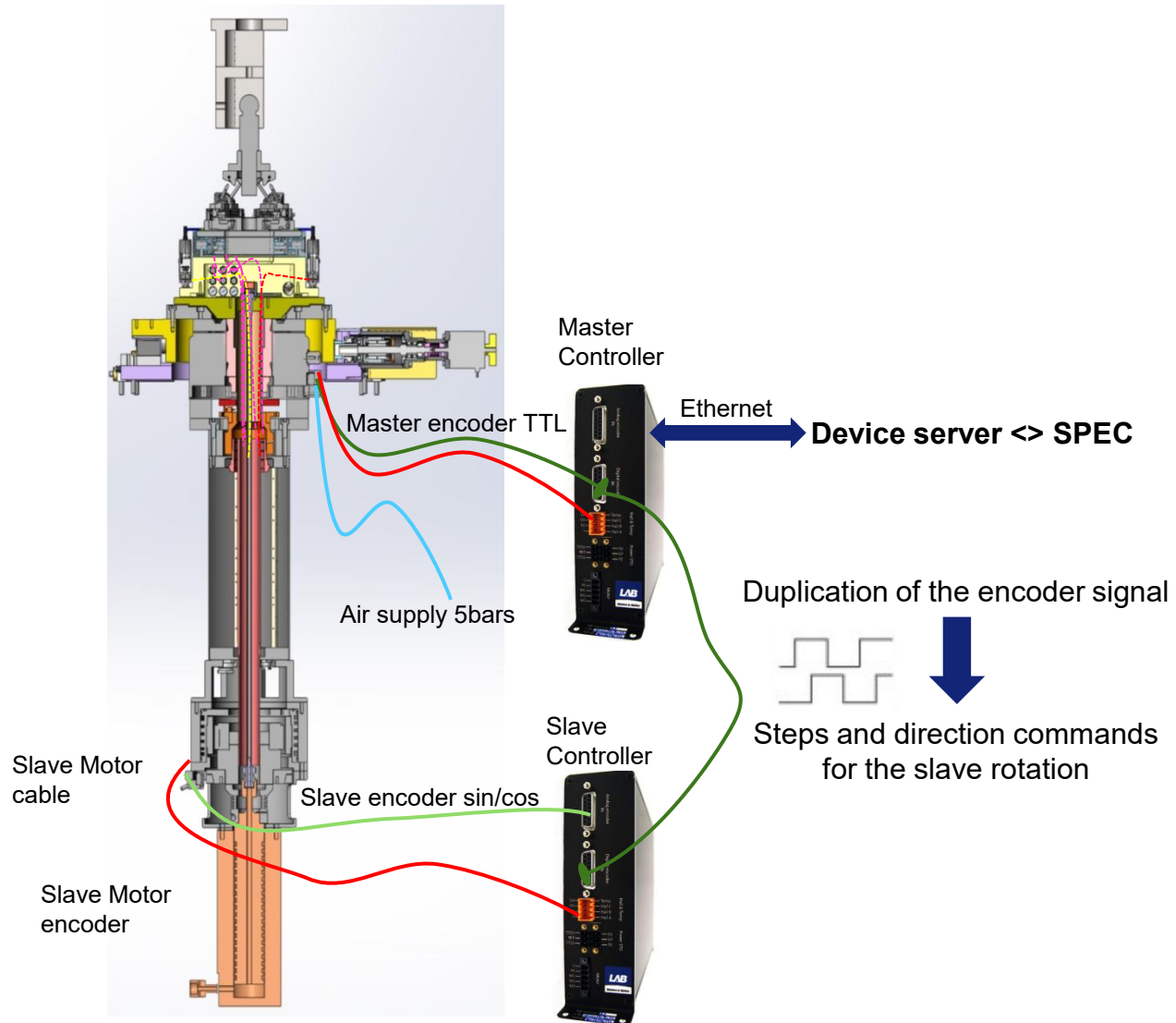
NO mechanical coupling between the slave and the master rotor (except the stiffness of the cables)

Slip-ring :
 Standard ball-bearings
 Resistive torque < 1Nm
 101 electrical ways for :
 -Capacitive probes 30kHz (PIMars)
 -Piezo actuators -30/135V (PIMars)
 -Piezo motors ±48V 10kHz (Nanopos)
 -RS422 encoder signals 1MHz (Nanopos)
 -15 auxiliary signals

Very good flatness of interfaces required [1-5] μm



III. Control Architecture – Rotation stage



III. Rotary stage – Metrology in BL working conditions

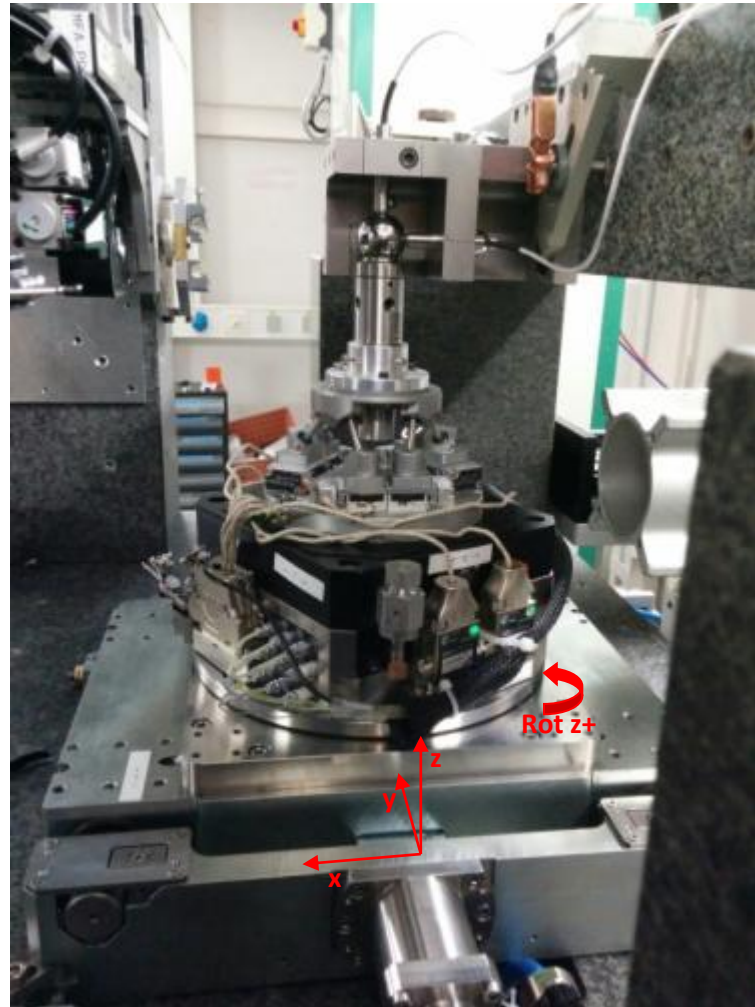
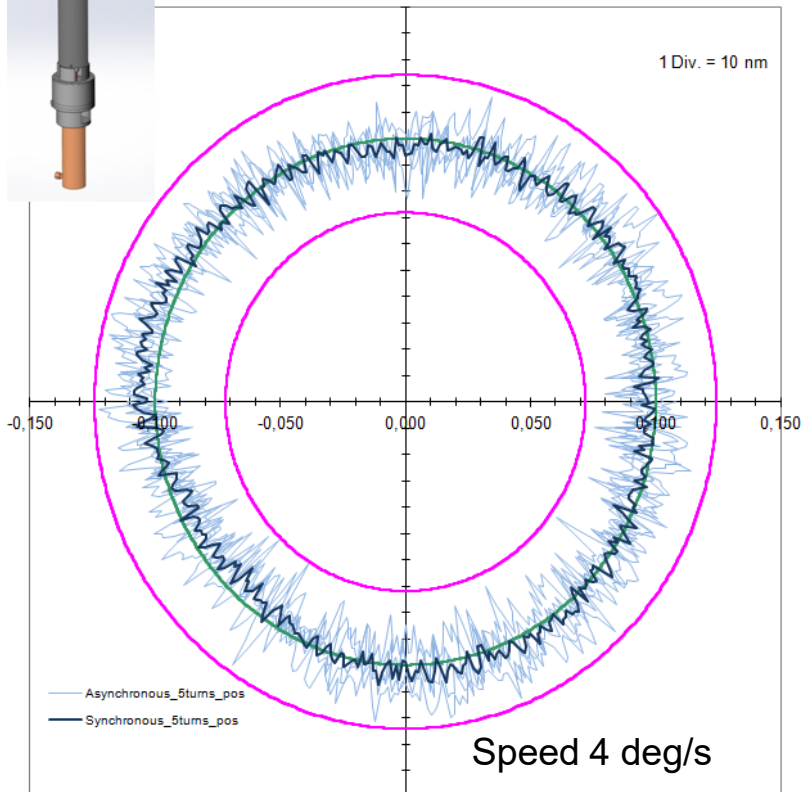
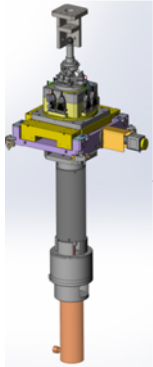
Rotary stage RT150up ID11 nanoscope Axial Error

Reference Sphere: Single diam. = 25.4 mm
h = 242mm (from the top face)

5 forward of full rotation (0 to 360 deg) - Meas. interval: 0,72 deg
continuous motion mode, after warm-up, without drift correct.
(500 points / turn - averaging 200 points @ 50kHz)

Date of measurement: 23/08/2016 - Operator : LD
Meas. system : Lion + SEA (low sensivity)

synchronous error : 23 nm
max. asynchronous error : 41 nm ($\theta=324^\circ$)



All sample stages activated in closed-loop
Dty-Rotation-PIMars-Nanopos

III. Rotary stage – Metrology in BL working conditions

Rotary stage RT150up ID11 nanoscope Radial Error

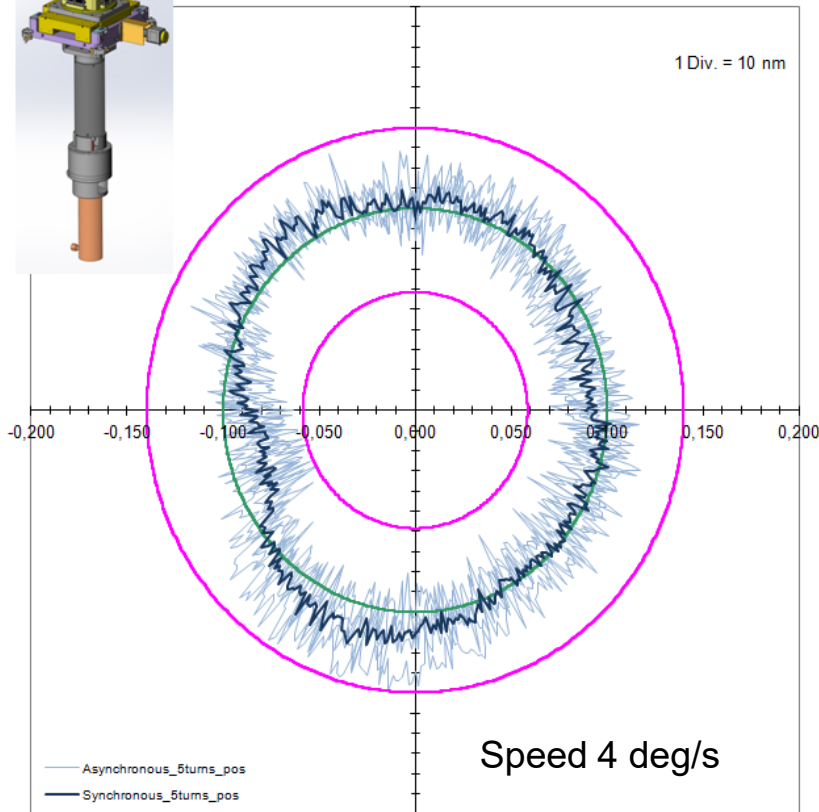
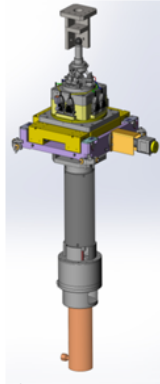
Rotating Sensitive Direction

Reference Sphere: Single diam. = 25.4 mm
h = 242mm (from the top face)

5 forward of 5 full rotation (0 to 360 deg) - Meas. interval: 0,72 deg
continuous motion mode, after warm-up
(500 points / turn - averaging 200 points @ 50kHz)

Date of measurement: 23/08/2016 - Operator : LD
Meas. system : Lion + SEA

min.synchronous error : 42 nm ($\varphi=180^\circ$)
max. asynchronous error : 55 nm ($\theta=208^\circ$)



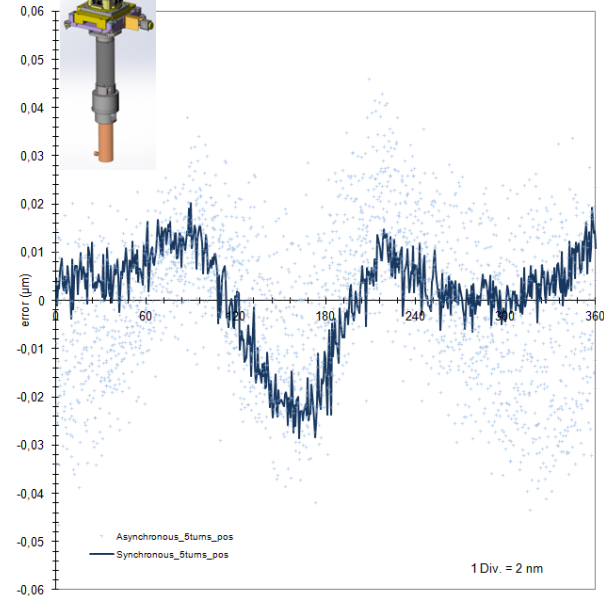
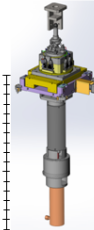
Radial Error Fixed Sensitive Direction Y

Reference Sphere: Single diam. = 25.4 mm
h = 242mm (from the top face)

5 forward of 5 full rotation (0 to 360 deg) - Meas. interval: 0,72 deg
continuous motion mode, after warm-up, without drift correct.
(500 points / turn - averaging 200 points @ 50kHz)

Date of measurement: 23/08/2016 - Operator : LD
Meas. system : Lion + SEA (low sensitivity)

synchronous error : 49 nm
max. asynchronous error : 64 nm ($\theta=344^\circ$)

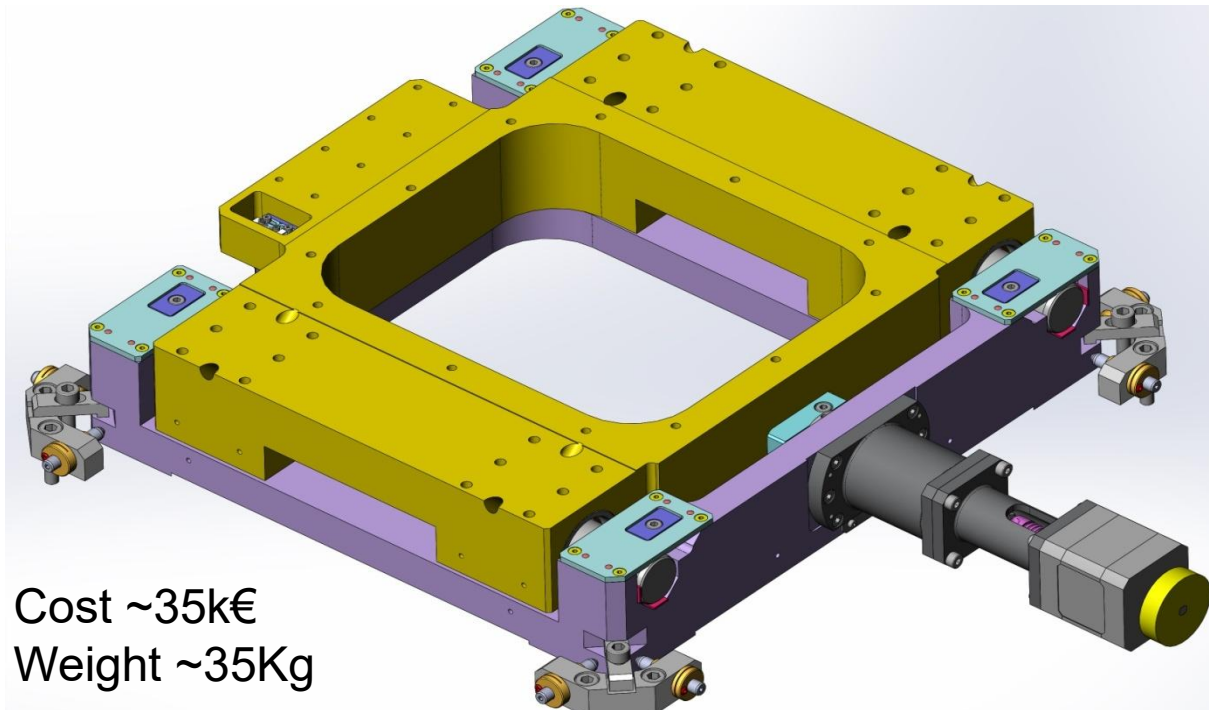


Asynchronous errors (repeatability) are larger than expected

➤ Mainly induced by an internal thermal drift in the RT150up (already visible during the characterization of the rotary stage standalone)

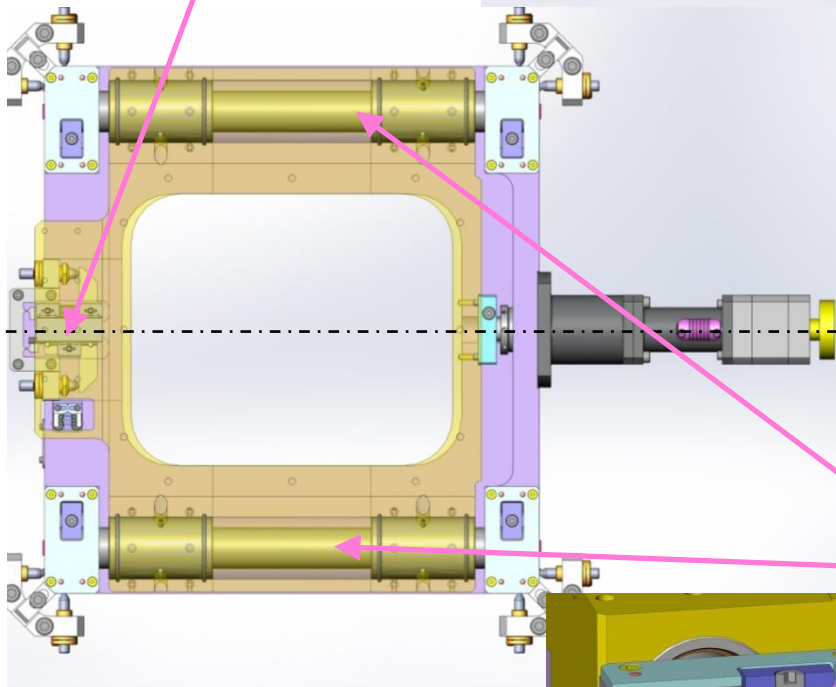
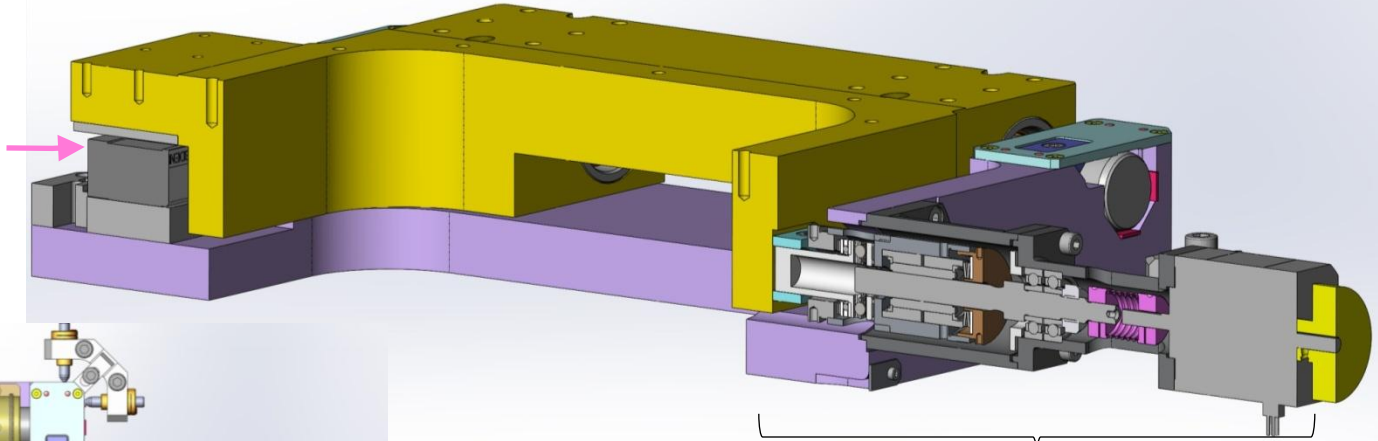
IV. DTy – A high precision Linear Stage designed and assembled at ESRF

DTy stage	SPECIFICATIONS (@ POI H ~250mm)
Stroke	10 mm
Speed	1mm/s
Carried load	37 kg
Accuracy	3 μm
Repeatability bidirectional (full stroke)	4 μm
Repeatability bidirectional (stroke 100μm)	10 nm
MIM	10 nm
Straightnesses full stroke	10 μm
Repeat. Straightnesses FS	1 μm
Pitch error full stroke	5 μrad
Repeat. pitch error FS	0.5 μrad



IV. DTy Linear stage – Mechanical Design

Heidenhain LIP281 encoder
Accuracy 20nm/10mm
Signal period 512nm
Interpol.x400 + quad : 0.32nm
Integration along the symmetrical plane



Stepper motor + satellite roller screw *Rollvis* + Oldham joint (balls) for alignment decoupling
No reduction gear
Standard stepper motor 400 steps/turn
Rollvis : pitch 1mm, preload adjusted during the integration

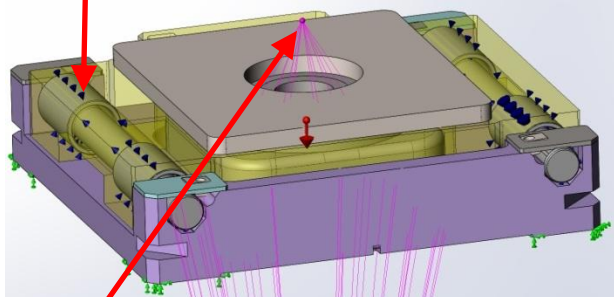
Frame components
Material C45E – Criteria: low ratio α/κ ($\alpha: 11 \cdot 10^{-6} \text{K}^{-1}$ $\kappa: 50 \text{ W/m.K}$)
and high stiffness ($E: 200 \text{ Gpa}$)
Thermal stabilisation before final machining

Ball-bush guidings (Mahr)

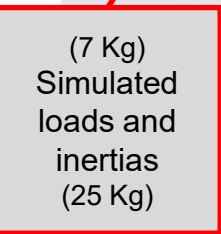
- Factory preload 2-3 μm
- Specific selection of components (Mahr) for linearity and coaxiality between rolling areas
- The 4 bushes are glued in the carrier in order to minimize the parasitic constraints after the assembly
- The // (<2 μm) between shafts is finely adjusted with the use of slip gages and iterative measurements on a CMM
- Optimised preloading of the shaft locking for low deformation

IV. DTy Linear stage – FEA calculations of Eigen frequencies

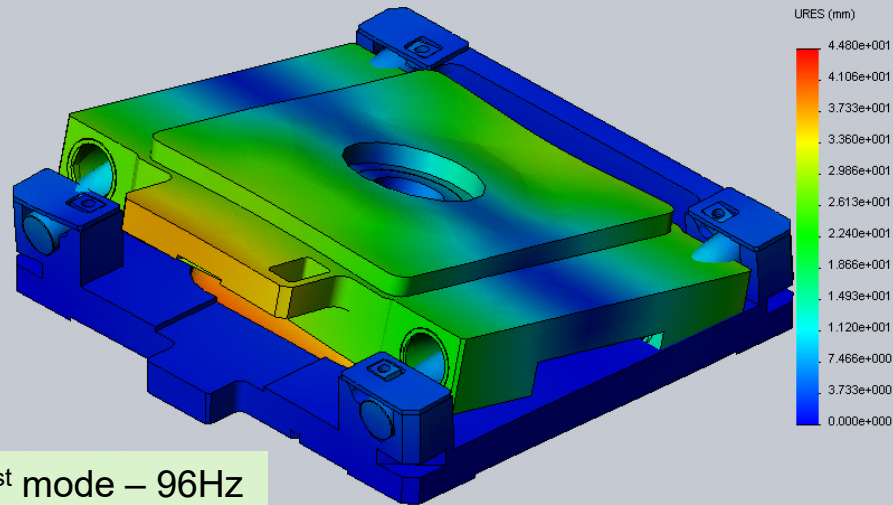
Calculated stiffness for ball-bush
 $K_{\text{radial}} = 425 \text{ N}/\mu\text{m}$



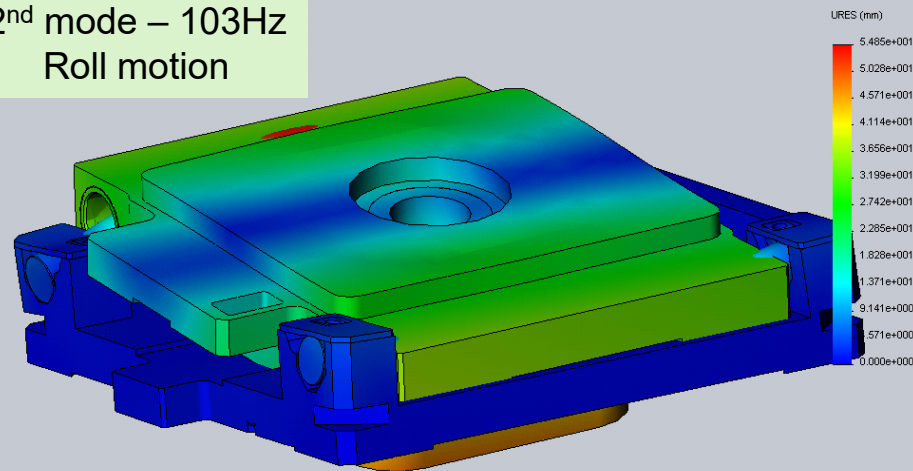
(7 Kg)
Simulated loads and inertias
(25 Kg)



1st mode – 96Hz
Pitch motion

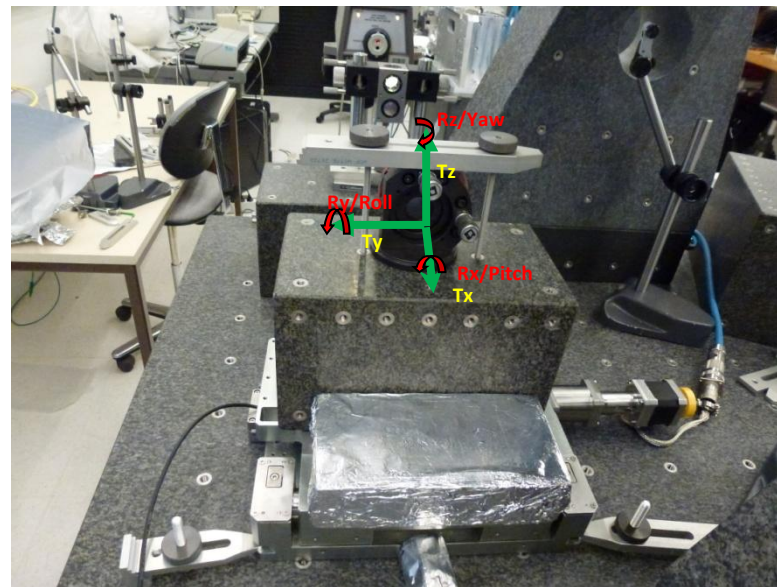


2nd mode – 103Hz
Roll motion

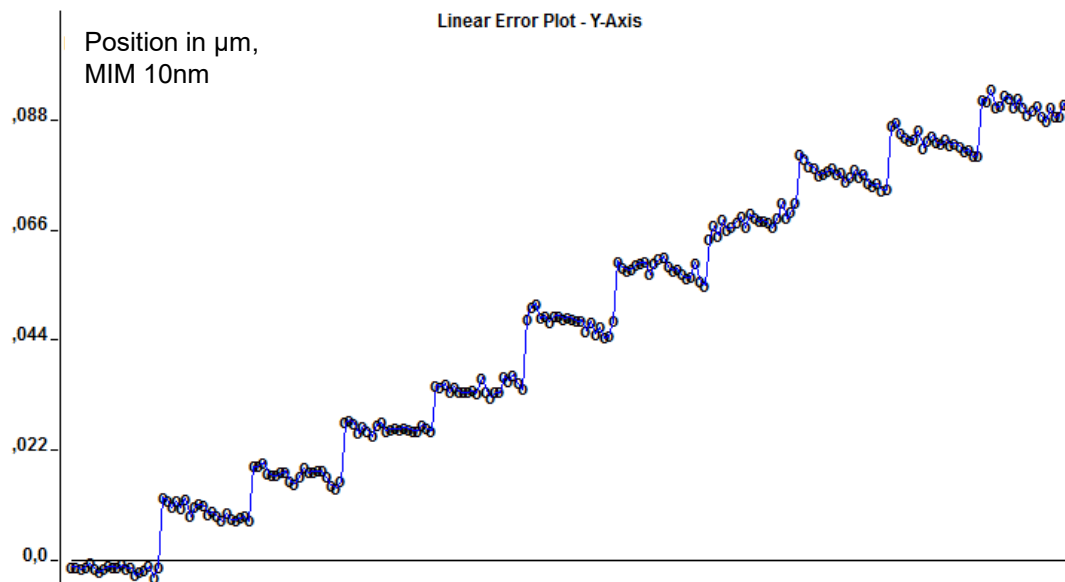


IV. DTy Linear stage – Metrology characterisation

DTy stage	PEL meas.	SPECS
Accuracy & repeat. full stroke	263 nm / R 50nm	3 μ m R4
Accuracy & repeat. stroke 100 μ m	66 nm / R 27nm	3 μ m R10nm
MIM positive or negative	6 nm	10 nm
Straightness horiz. full stroke	37 nm / R 33nm	10 μ m R1
Straightness horiz. stroke 100 μ m	22 nm / R 20nm	/
Straightness vertic. full stroke	212 nm / R 115 nm	10 μ m R1
Straightness vertic. Stroke 100 μ m	27 nm / R 27nm	/
Pitch error Ryx full stroke	2.9 μ rad / R 0.39 μ rad	5 μ rad R0.5
Yaw error Ryz full stroke	4.5 μ rad / R 0.33 μ rad	/
Roll error Ryy full stroke	1.23 μ rad / R 0.93 μ rad	/
Accuracy & repeat full stroke @ Height 50mm and without load	47 nm / R 23nm	/



Measurement near the POI
H = 200 mm



- ✓ An electrical slip-ring can pass sensitive signals
 - ✓ The concept of integration used with the high precision rotary stage has no significant effect on the error motions
 - ✓ A specific but simple linear stage can achieve a very high precision without any complex control systems
 - ✓ The RT150up stage can achieve very low motion errors
- ✗ The thermal drifts of the rotary stage are not only along the linear axes
- ✗ Improvements are possible :
- reduction of heat sources
 - improvement of air-supplying distribution
 - thermal control of the RT150up frame
 - active compensation of error motions

Thank you for your attention

Any questions ?

Acknowledgments

BL Team : Jonathan Wright – Henri Gleyzolle – José-María Clément – Emmanuel Papillon

AAM Group : Yves Dabin – (ID16B end-station concept)

PDMU-PEL Metrology Lab : Hans-Peter van der Kleij – Léo Rousset

PAMU Assembly Lab : Giovanni Malandrino – Robin Grégoire – Rodolphe Grivelet

Subcontracted Design & Drafting : Catherine Heyman (*Design & Mécanique*) – SEI